

EUROPEAN
PLASMA RESEARCH
ACCELERATOR WITH
EXCELLENCE IN
APPLICATIONS



WP4: Laser Design and Optimization

Overview of latest developments and critical issues

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On behalf of WP4

EuPRAXIA Retreat in the Alps

26th February 2019, Grainau, Germany



<http://eupraxia-project.eu>



This project has received funding from the European Union's Horizon 2020 research and innovation programme under grant agreement No 653782.

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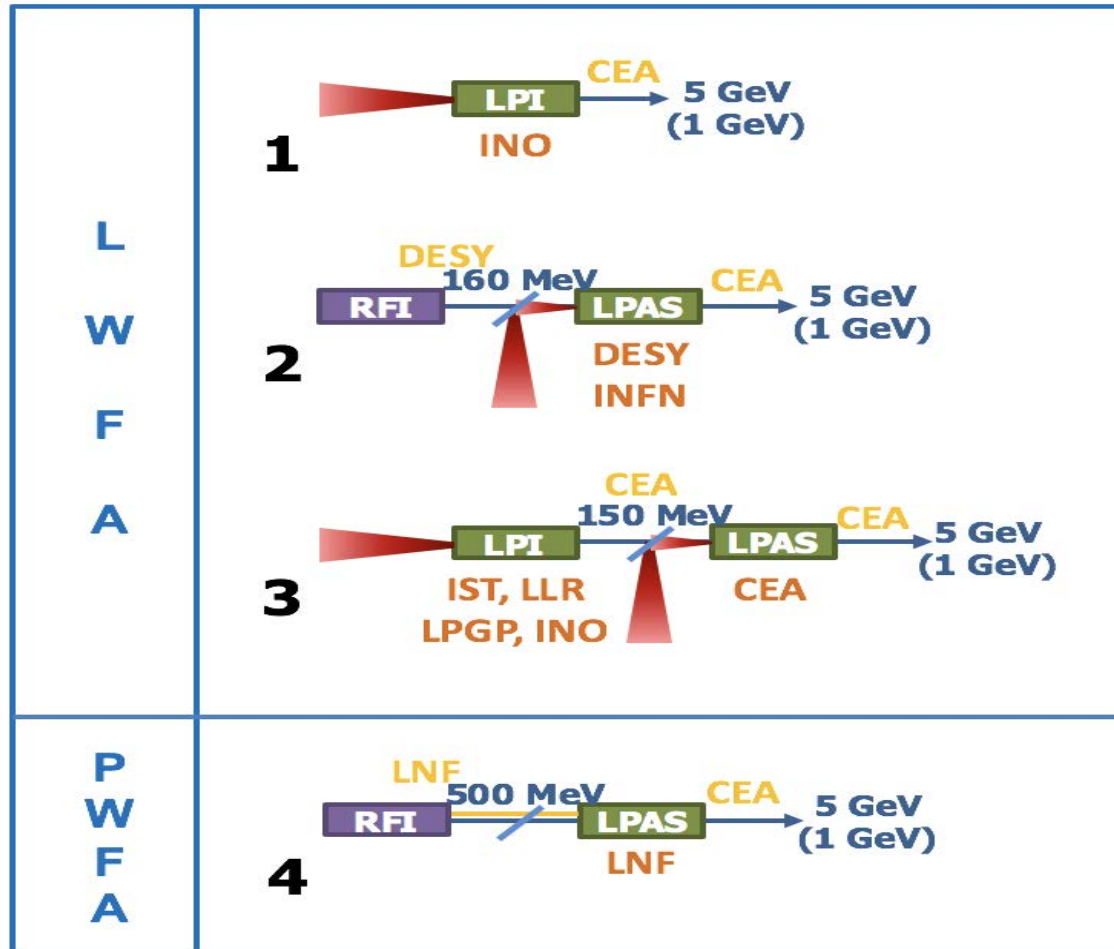
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— industries
 — laboratories
 shaded major contributors/collaborators

- EuPRAXIA laser requirements and strategy
- Baseline design
- Options
- Conclusions

Acceleration schemes (WP2), selected to provide a beam at **5 GeV** meeting FEL and HEPO requirements and a beam at **1 GeV** 'usable' for FEL and HEPO, as a 'commissioning' step.



Injector Laser 150 MeV – LASER 1

| Laser 1 - Injector 150 MeV | | | | |
|--|---------------------------|-----------|-----------|--|
| Parameter | Label | P0 | P1 | |
| Wavelength (nm) | λ (nm) | 800 | 800 | |
| Maximum energy on target (J) | E_{target} | 5 | 7 | |
| Maximum output energy (J) | E_{out} | 8.8 | 12.5 | |
| Energy tuning resolution (% of targeted value) | dE | 7 | 5 | |
| Total output energy (incl. Diagnostic beams) | E_{tot} | 7 | 10 | |
| Pulse length (FWHM) (fs) | τ | 30 | 20 | |
| Repetition rate (Hz) | f | 20 | 100 | |
| Requirement on energy stability (RMS) % | $\sigma\langle E \rangle$ | 1 | 0.6 | |

Injector Laser 1GeV – LASER 2

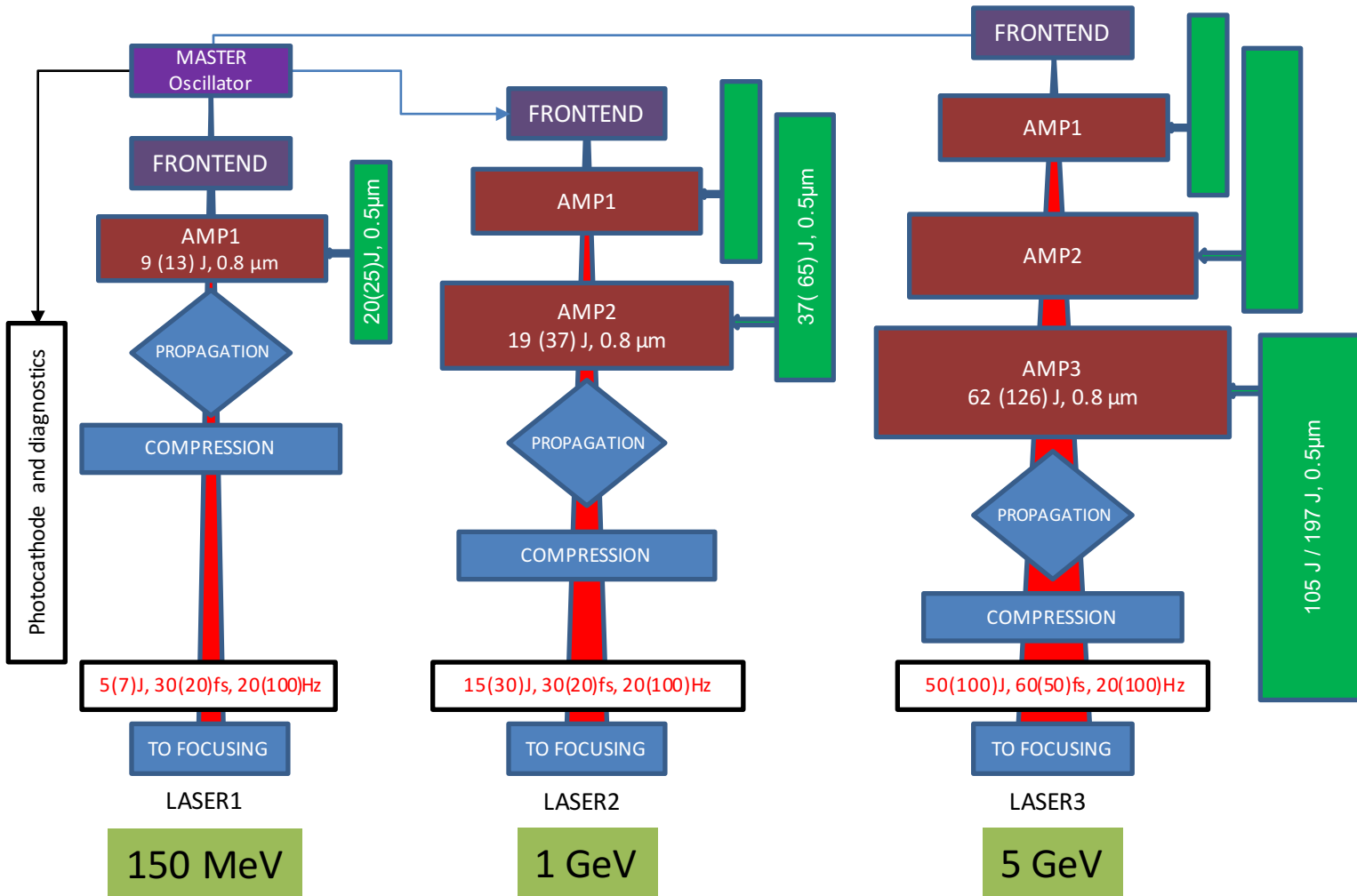
| LPI/LPA - Injector 1 GeV | | | | |
|--|------------------------------|-----------|-----------|--|
| Parameter | Label | P0 | P1 | |
| Wavelength (nm) | λ (nm) | 800 | 800 | |
| Maximum energy on target (J) | E_{target} | 15 | 30 | |
| Maximum output energy (J) | E_{out} | 18.8 | 37.5 | |
| Energy tuning resolution (% of targeted value) | dE | 7 | 5 | |
| Shortest pulse length (FWHM) (fs) | τ | 30 | 20 | |
| Repetition rate (Hz) | f | 20 | 100 | |
| Requirement on energy stability (RMS) % | $\sigma_{\langle E \rangle}$ | 1 | 0.6 | |

Accelerator Laser 5GeV – LASER 3

| LPA - Driver 5 GeV | | | | |
|--|------------------------------|-----------|-----------|--|
| Parameter | Label | P0 | P1 | |
| Wavelength (nm) | λ (nm) | 800 | 800 | |
| Maximum energy on target (J) | E_{target} | 50 | 100 | |
| Maximum output energy (J) | E_{out} | 62.5 | 125 | |
| Energy tuning resolution (% of targeted value) | dE | 7 | 5 | |
| Shortest pulse length (FWHM) (fs) | T | 60 | 50 | |
| Repetition rate (Hz) | f | 20 | 100 | |
| Requirement on energy stability (RMS) % | $\sigma_{\langle E \rangle}$ | 1 | 0.6 | |

- **Originally driven by boundary conditions:**
 - Beyond state of the art;
 - Laser with unique (rep-rated) performance;
 - Industry to provide the laser;
 - High Technology Readiness Level;
 - Timescale of development (5 yrs)
- Involve leading industry and research labs;
- Reach consensus on baseline configuration;
- Down-select emerging technology components;
- Identify R&D for critical components;
- Develop full CDR of baseline;
- Evaluate investment and running costs.
- **Include options to account for:**
 - Evolutionary baseline configuration;
 - Higher efficiency, higher repetition rate.

Titanium-Sapphire system with diode-pumped pump lasers



- **Design guidelines**

- Modularity: possibility to use the same amplification stages in the different laser chains
- Scalability: possibility to upgrade from P0 to P1 performance level, “simply” by increasing pump energy and rep rate (conservative design at P0)
- **High extraction efficiency (esp. at P1) to reduce pump energy requirements**
- **Thermal management issues**

- **Methodology**

- Evaluation of the amplification parameters (energy, spectrum, beam size, stability, parasitic lasing) with **numerical simulations** (MIRO – CEA);
- Validation of modelling with existing systems up to multi-J level;
- Preliminary thermomechanical evaluation by means of FEA simulations (LAS-CAD);

- **Results**

- Main parameters for each stage: pump energy, extracted energy, beam size, spectral shift, parasitic gain
- Energy stability vs pump and seed energy fluctuations
- Evaluation of thermal aberrations
- Cooling strategies: liquid flow cooling
- ASE/PL mitigation strategies: Extraction during pumping

G. Toci

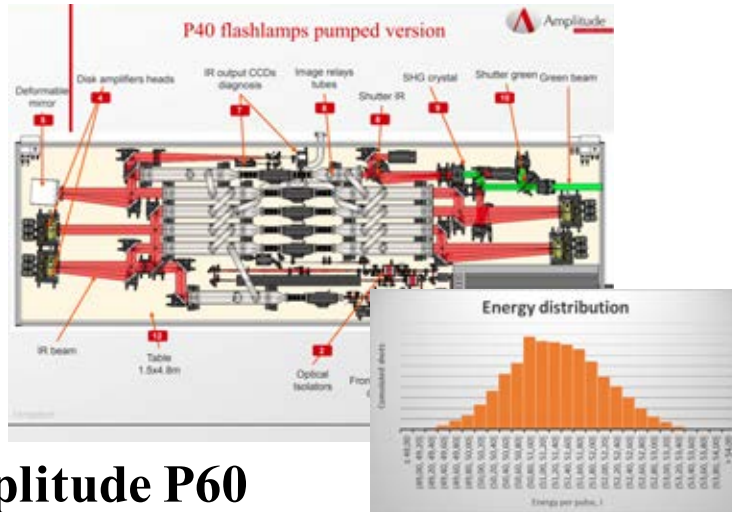
Power amplifiers require **high average power pump lasers**

| | Target E (J) | Out E (J) | PRF (Hz) | Seed E (J) | Design Out E (J) | 0.5 μ m Pump Pulse E (J) | Extr. Eff. (%) | <P> (532 nm) (kW) | Thermal Load (kW) | IR Pulse E (J) | <P> (1 μ m) (kW) |
|------------------|--------------|-----------|----------|------------|------------------|------------------------------|----------------|-------------------|-------------------|----------------|----------------------|
| LASER1 (AMP1) P0 | 7,0 | 8,8 | 20 | 1,5 | 8,9 | 19,2 | 39 | 0,4 | 0,2 | 27,4 | 0,5 |
| LASER1 (AMP1) P1 | 10,0 | 12,5 | 100 | 1,5 | 12,7 | 25,7 | 44 | 2,6 | 1,3 | 36,7 | 3,7 |
| LASER2 (AMP2) P0 | 15,0 | 18,8 | 20 | 6,3 | 19,1 | 37,2 | 35 | 0,7 | 0,4 | 53,1 | 1,1 |
| LASER2 (AMP2) P1 | 30,0 | 37,5 | 100 | 8,8 | 37,5 | 65,2 | 44 | 6,5 | 3,3 | 93,1 | 9,3 |
| LASER3 (AMP3) P0 | 50,0 | 62,5 | 20 | 18,8 | 62,4 | 105,0 | 42 | 2,1 | 1,1 | 150,0 | 3,0 |
| LASER3 (AMP3) P1 | 100,0 | 125,0 | 100 | 37,5 | 126,0 | 197,0 | 45 | 19,7 | 9,9 | 281,4 | 28,1 |

Total fundamental wavelength average pump power ranges from **3 kW** (20 Hz) to **30 kW** (100 Hz)

- Follow industrial developments of high average power pump lasers;
- Motivate DPSSL implementation on currently available industrial flash-lamp pumped systems for 10 Hz performance;
- Link to available effort in prototyping from research labs for enhanced performance (20 Hz);
- Attract new resources for **high power diode developments** for future 100 Hz upgrade.

Promising developments based on diode pumping technology are in progress at EuPRAXIA industrial and research partners, progressively matching requirements



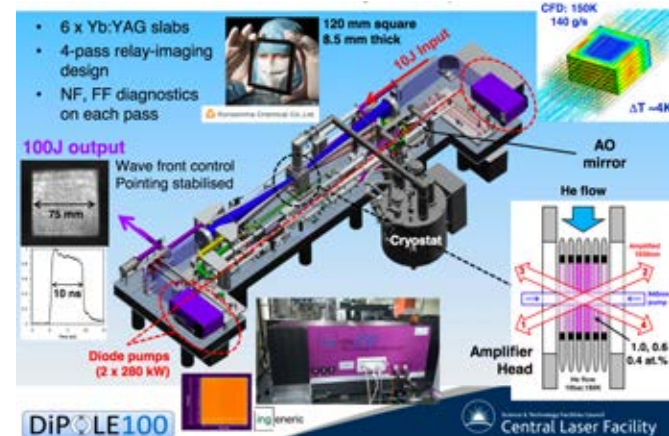
Amplitude P60

Flashlamp pumped Nd:YAG

Design: 60 J @ 10 Hz, 532 nm

Conversion to DPSS fully designed

- Expected rep. rate 50 Hz
- Cost of diode still an issue – currently 5x compared to flashlamps.
- Expected to decrease in 5-10 yrs.
- Maintenance free operation for 25-30 yrs.



DIPOLE⁽¹⁾ 100 @ CLF-STFC

DPSSL Yb:YAG, cryogenic He cooling

100 J @ 10 Hz, @515 nm

Planned developments: 10J @ 100 Hz

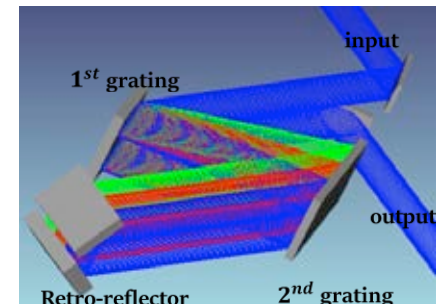
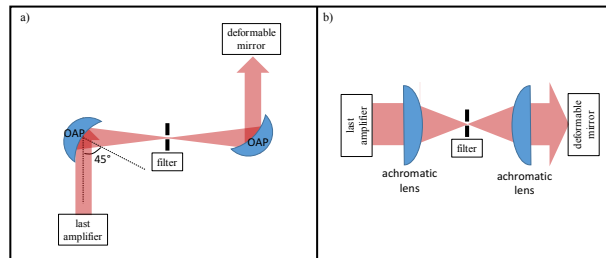
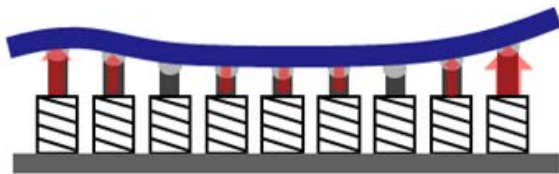
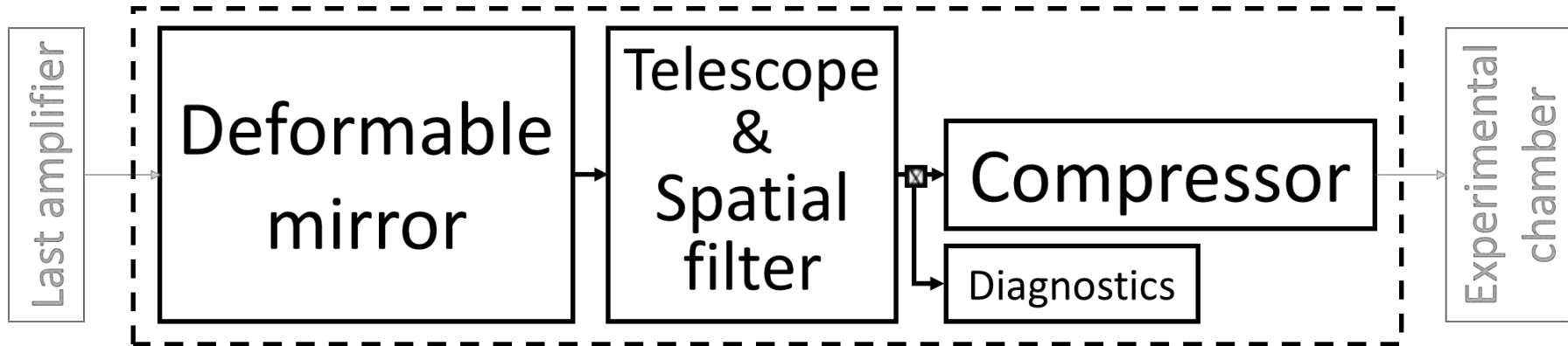
Established at 10 Hz

Route to 20 Hz pumping for EuPRAXIA:

Angular multiplexing

¹P. Mason et al., "Kilowatt average power 100J-level diode pumped solid state laser," Optica 4, 438-439 (2017)

Main challenges: large optics, **mechanical stability**, **cooling of gratings**, beam quality control ...

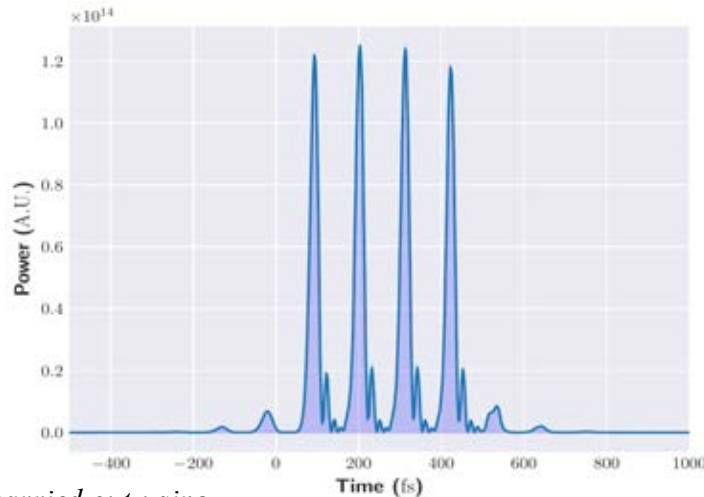


Different grating technologies under evaluation to address main issues with higher repetition rate. Strategy includes **reduction** of the thermal load at high average power, **cooling** of residual heat and **control** of thermal effects on compression quality.

A (QUASI) LOSSLESS SCHEME

Motivation. Shortcomings of current proposed/employed schemes

- Complex setup, to be implemented on the compressed (large) beam
- Intensity homogeneity issues among the different pulses of the same train
- Possibly leading to very high energy losses (up to 50%) ← relevant for the EuPRAXIA laser design



Simulation carried out using the MIRO code

Quasi lossless Train generation by an early aMplitude dIvision (TEMPI) [2]

Splitting occurs very early in the laser chain. Effects due to pulse interference manageable

L. Labate

Test experiment in progress at CNR ILIL laboratory

Energy losses negligible as compared to the overall pump energy
Compact and simple setup

White paper 100 Hz pump trials to assist EuPRAXIA system design (STFC, LLNL, HZDR, FBH), supported by the Institute of Quantum Optics, Friedrich-Schiller-University, Jena in Germany

FBH brilliant high duty cycle pump: small-series prototype

Novel chip, carrier



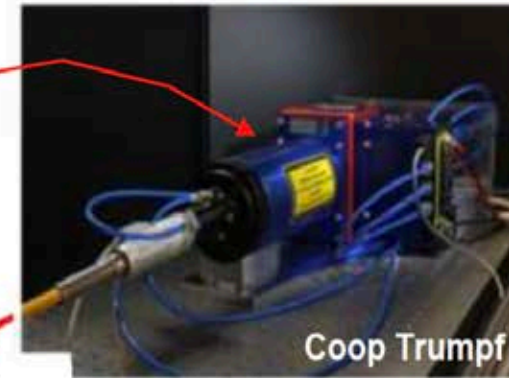
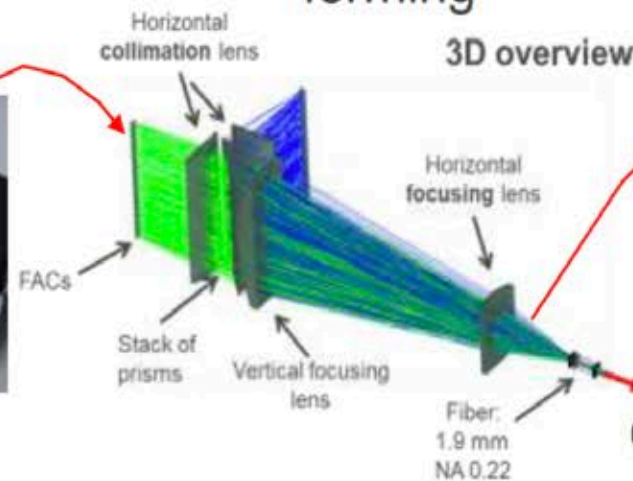
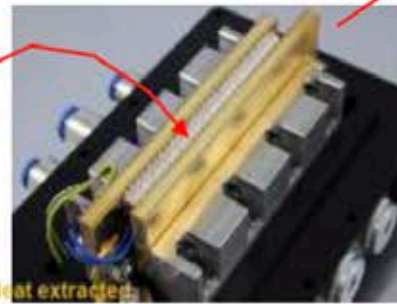
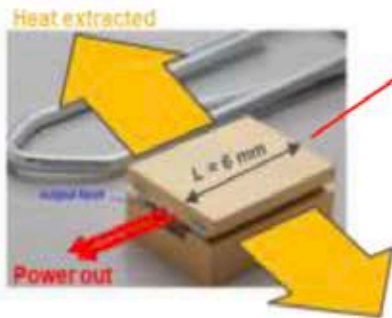
Novel passive Side cooler



Custom beam forming



Brilliant, high duty cycle fibered module



130W from 1.2mm
Peak: ~ 245 W
60% efficiency
2x brighter than bars

1...20% DC
1...100ms
Passive cooling

P. Crump

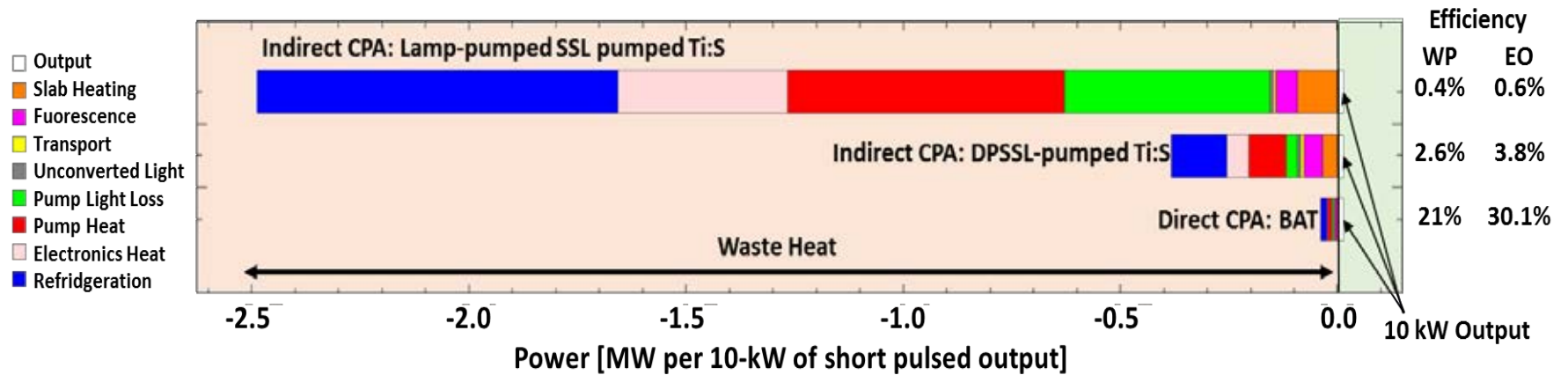
6 kW 60% efficiency
 $M^2 \sim 300 \times 300$

1.4 MW/cm²-sr
50% efficiency
 $M^2 \sim 700$

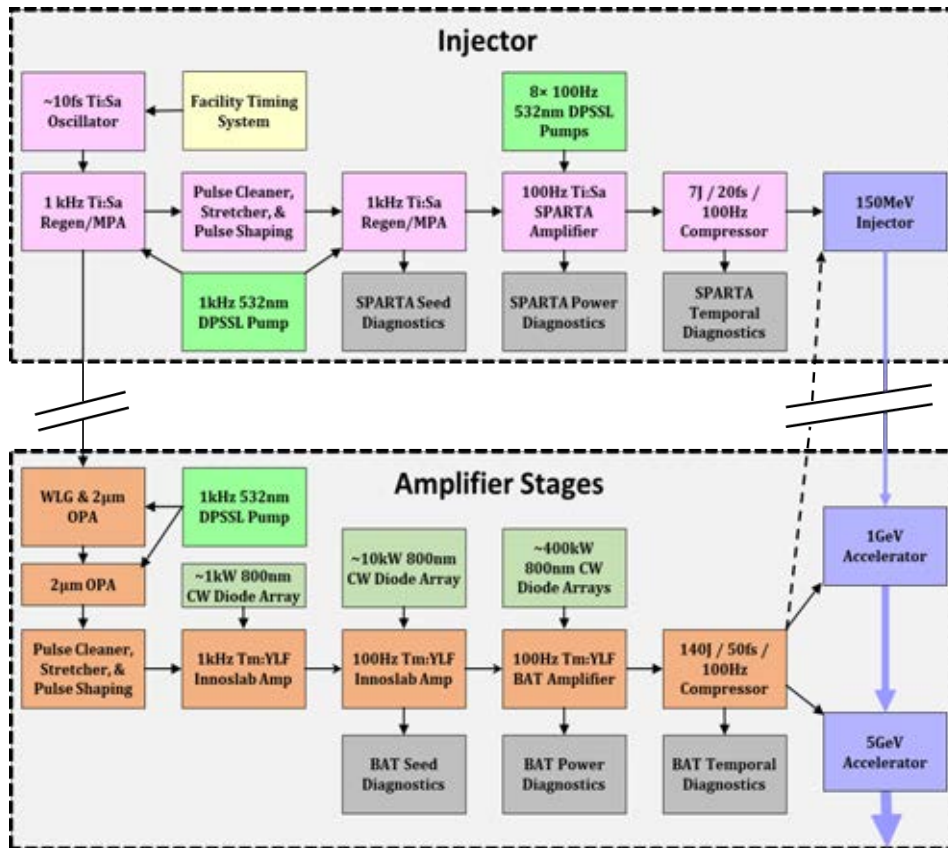
6 units delivered to Max Born Institut, Berlin; 2 in build

- Plasma accelerators will require high repetition lasers with high efficiency. Direct pumping of lasing medium with diodes is the solution.

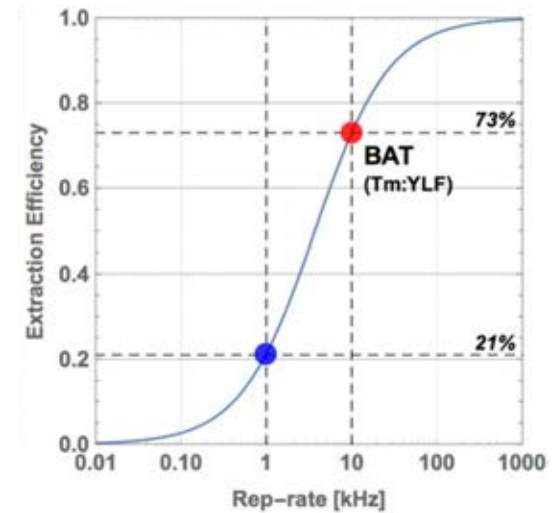
Direct CPA (required for >100Hz) - energy efficient.



Tm:YLF: Big-Aperture-Thulium Laser (BAT*)

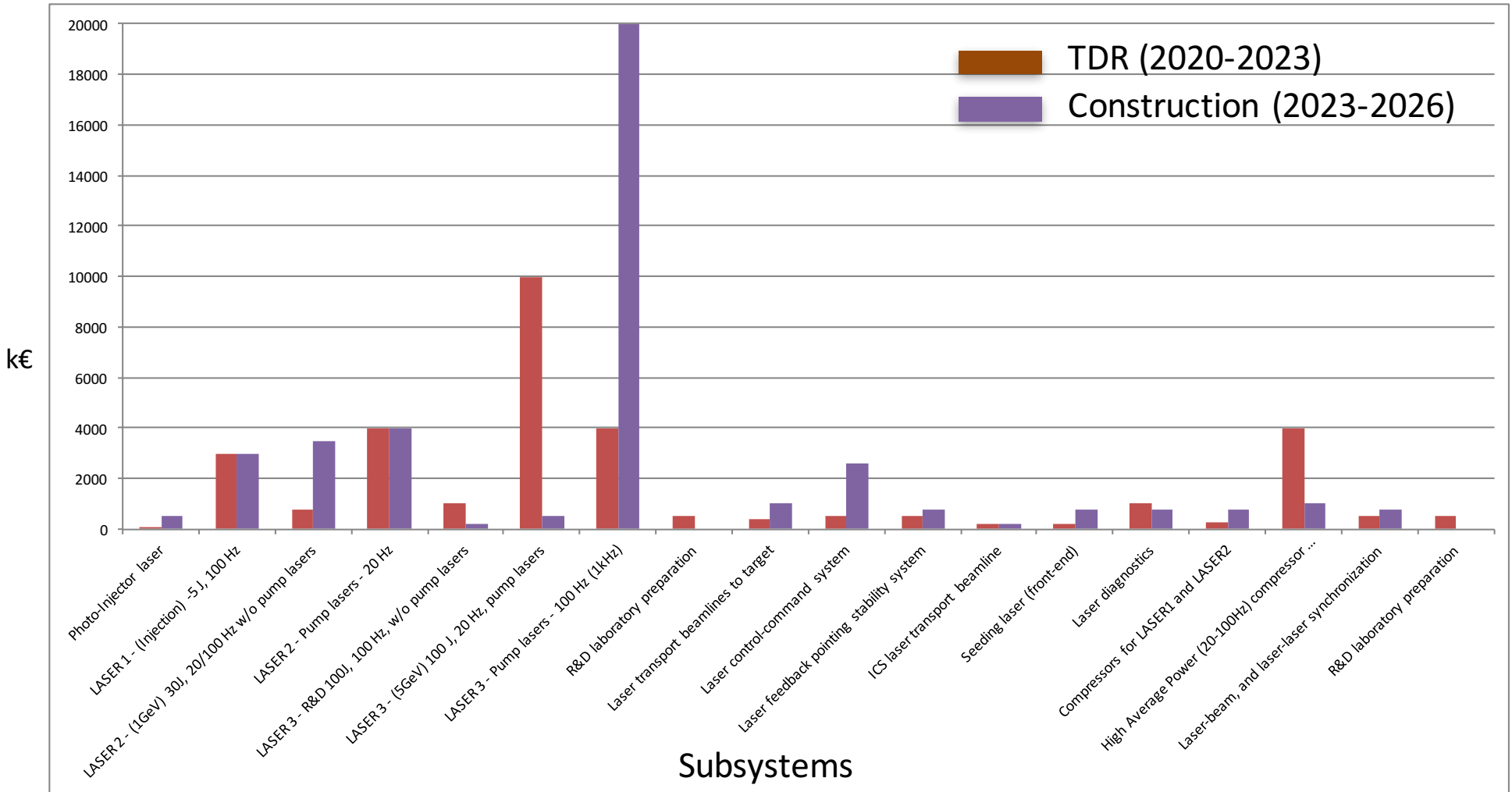


Laser system designed to deliver 7J/30fs/230TW at 100Hz : average power of this system = 700W



- Central wavelength at 1.9 μm,
- Pulse duration potentially as short as 50 fs
- WPE very high for >10 kHz (<5% at 100 Hz)
- Issues remain for LWFA at 1.9 μm

R&D and Investment



| subtopic | TDR/prototyping (e.g. 2020 - 2023) | | Construction (e.g. 2023 - 2026) | | Local facility used for R&D, prototyping and tests (name of facility) | comment |
|---|------------------------------------|------------------|------------------------------------|------------------|--|--|
| | personnel (cumulative for 4 years) | material (total) | personnel (cumulative for 4 years) | material (total) | | |
| | [FTE] | [k€] | [FTE] | [k€] | | |
| R&D (please specify in comments) | | | | | | R&D is dedicated to finalize the technology considered for the technical design. During the R&D phase we consider construction of an entire chain (LASER3) prototype at 20 Hz. Construction phase will use prototype components to build the whole system - LASER1, LASER2, LASER3. |
| Photo-Injector laser | 2 | 100 | 4 | 500 | CNRS, Paris | Scale existing schemes |
| LASER 1 - (Injection) -5 J, 100 Hz | 4 | 3000 | 8 | 3000 | CNR-INO, Pisa | This will be based on industrial systems and will be developed with laser industry. The prototyping of LASER1 includes the front-end which will then be replicated for LASER2 and This will be developed in close collaboration with Laser Industry. Here most of the cost for the construction phase is dedicated to diode stacks |
| LASER 2 - (1GeV) 30J, 20/100 Hz w/o pump lasers | 8 | 800 | 8 | 3500 | CNR-INO, Pisa | This involves industry and other institutes including , STFC, IOQ Jena, Here most of the cost for the construction phase is dedicated to diode stacks |
| LASER 2 - Pump lasers - 20 Hz | 4 | 4000 | 4 | 4000 | FBH Berlin(?) | This involves industry and a collaboration including FBH, STFC, IOQ-JENA ... Here most of the cost for the construction phase is dedicated to diode stacks |
| LASER 3 - R&D 100J, 100 Hz, w/o pump lasers | 8 | 1000 | 12 | 200 | CNR-INO, Pisa | This will be developed in close collaboration with Laser Industry. |
| LASER 3 - (5GeV) 100 J, 20 Hz, pump lasers | 8 | 10000 | 12 | 500 | CNR-INO, Pisa | This will be developed in close collaboration with Laser Industry. Here most of the cost for the construction phase is dedicated to diode stacks |
| LASER 3 - Pump lasers - 100 Hz (1kHz) | 16 | 4000 | 16 | 20000 | FBH Berlin(?) | This involves industry and a collaboration including FBH, STFC, IOQ-JENA ... Here most of the cost for the construction phase is dedicated to diode stacks |
| R&D laboratory preparation | 4 | 500 | 0 | 0 | CNR-INO, Pisa | |
| Laser transport beamlines to target | 6 | 400 | 8 | 1000 | CNRS, Paris | |
| Laser control-command system | 16 | 500 | 16 | 2600 | CNRS, Paris | |
| Laser feedback pointing stability system | 8 | 500 | 8 | 800 | CNRS, Paris | This will be developed in collaboration with STFC and other applicable facilities |
| ICS laser transport beamline | 4 | 200 | 8 | 200 | CNR-INO, Pisa | ICS laser will be based on one of the three main beamlines, with custom management |
| Seeding laser (front-end) | 8 | 200 | 4 | 800 | CNR-INO, Pisa | |
| Laser diagnostics | 8 | 1000 | 8 | 800 | CNRS, Paris | Only final diagnostics : after compressor and at the focal plan : full aperture, near and far field, pulse duration, energy, contrast Spatio spectral |
| Compressors for LASER1 and LASER2 | 6 | 250 | 4 | 800 | CNRS, Paris | |
| High Average Power (20-100Hz) compressor (Laser3) | 12 | 4000 | 6 | 1000 | CNRS, Paris | This will be developed in close collaboration with Laser Industry. |
| Laser-beam, and laser-laser synchronization | 12 | 500 | 8 | 800 | DESY, Hamburg | |
| R&D laboratory preparation | 4 | 500 | 0 | 0 | CNRS, Paris | |
| Partial Total | 134 | 30950 | 134 | 40500 | | |

Eupraxia Cost of ownership @ 20Hz

50J @ 532nm @ 20Hz (300 days per year @ 20H a day - expected diodes lifetime = 5×10^9 shots e.g 12.5 years @ 20Hz)

| | | | | per year | Per year/ watt |
|---|--------------------------------|--|--------------|--------------|-----------------|
| 1 | Recurrent costs | | | 214 545,45 € | 214,55 € |
| 2 | Diode replacement (12.5 years) | | | 327 600,00 € | 327,60 € |
| | | | Total | | 542,15 € |

Eupraxia Cost of ownership @ 50Hz

50J @ 532nm @ 50Hz (300 days per year @ 20H a day - expected diodes lifetime = 5×10^9 shots e.g 5 years @ 50Hz)

| | | | | per year | Per year/ watt |
|---|-----------------------------|--|--------------|--------------|-----------------|
| 1 | Recurrent costs | | | 214 545,45 € | 85,82 € |
| 2 | Diode replacement (5 years) | | | 819 000,00 € | 327,60 € |
| | | | Total | | 413,42 € |

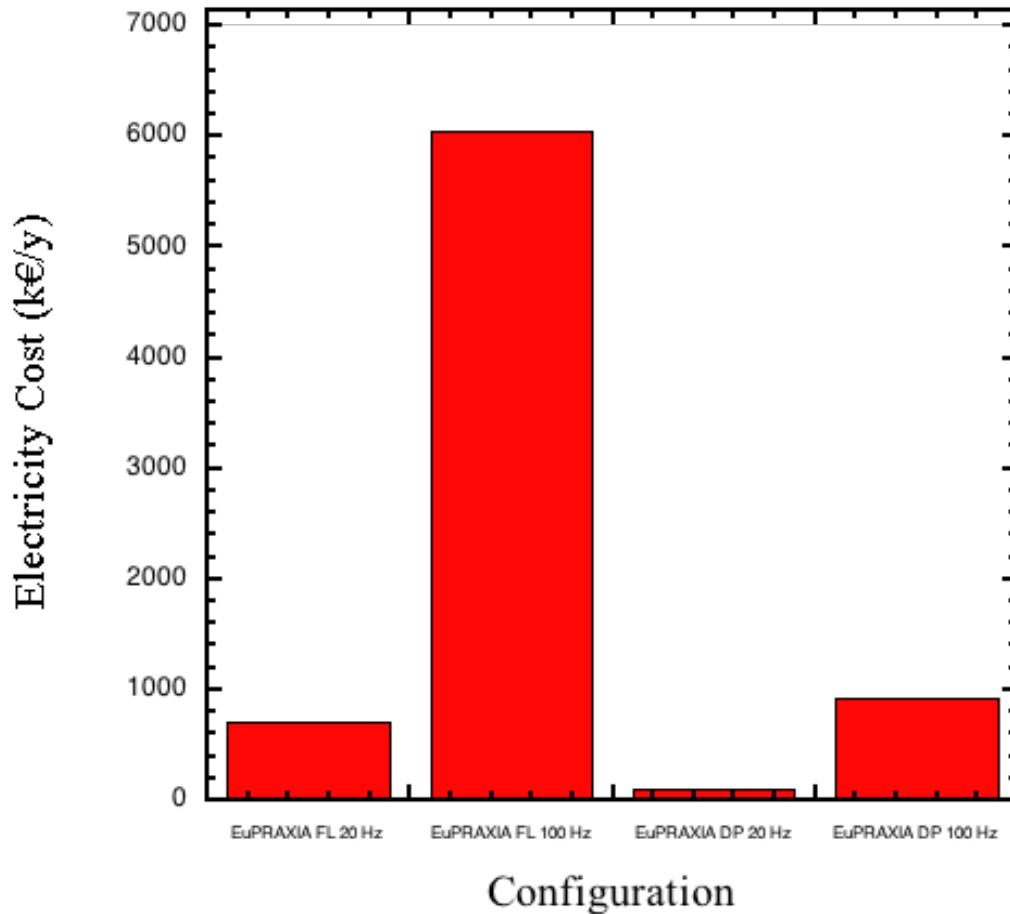
Eupraxia Cost of ownership @ 100Hz

50J @ 532nm @ 100Hz (300 days per year @ 20H a day - expected diodes lifetime = 5×10^9 shots e.g 2.5 year @ 100Hz)

| | | | | per year | Per year/ watt |
|---|------------------------------|--|--------------|----------------|-----------------|
| 1 | Recurrent costs | | | 214 545,45 € | 42,91 € |
| 2 | Diode replacement (2.5 year) | | | 1 638 000,00 € | 327,60 € |
| | | | Total | | 370,51 € |

Evaluated for the Amplitude P60 System

Scaling from efficiency of systems comparing
 flashlamp pumped (0.4%),
 indirect diode pumping (2.5%) 6.5X,
 eventually evolving towards direct CPA (21%) 9,1X.



| Configuration | Total pump power (kW) | Wall Plug Power (kW) | Electricity Cost (k€/y) |
|-----------------------|-----------------------|----------------------|-------------------------|
| laser1 FL 20 Hz | 0,384 | 96 | 58 |
| laser2 FL 20 Hz | 1,128 | 282 | 169 |
| laser3 FL 20 Hz | 3,228 | 807 | 484 |
| laser1 FL 100 Hz | 2,57 | 643 | 386 |
| laser2 FL 100 Hz | 9,09 | 2273 | 1364 |
| laser3 FL 100 Hz | 28,59 | 7148 | 4289 |
| laser1 DP 20 Hz | 0,384 | 15 | 9 |
| laser2 DP 20 Hz | 1,128 | 43 | 26 |
| laser3 DP 20 Hz | 3,228 | 124 | 74 |
| laser1 DP 100 Hz | 2,57 | 99 | 59 |
| laser2 DP 100 Hz | 9,09 | 350 | 210 |
| laser3 DP 100 Hz | 28,59 | 1100 | 660 |
| FULL System FL 20 Hz | 4,740 | 1185 | 711 |
| FULL System FL 100 Hz | 40,25 | 10063 | 6038 |
| FULL System DP 20 Hz | 4,740 | 182 | 109 |
| FULL System DP 100 Hz | 40,25 | 1548 | 929 |

Reduction of electricity running costs due to higher diode efficiency

- Prototyping of Ti:Sa amplifiers
- Addressing 100 Hz pump lasers developments
- Thermal management of compressor gratings
- Stability (pointing & more) and active control
- Driver pulse temporal shaping (multi-pulse)
- Synchronization
- Construction
- Integration Issues
- ...

**Seed funding planned by internal collaboration.
De-risking R&D phase expected prior to TDR.**

Cluster on laser technology (EuP-LASTECH):

R&D on laser drivers, prototyping, tests, construction of final hardware ...

Institutes: key WP4 participants and associated labs

TDR development issues

- **Amplifier configuration (\$\$):**
 - Build a test amplifier to test Thermal load, Cooling;
- **Pumping technology (\$\$\$):**
 - Scaled 100 Hz rep rep. rate, high energy pumping;
- **Grating technology (\$\$)**
 - Run high average power illumination tests at existing facilities, to make assessments on LIDT, Thermal load, Cooling. Lifetime;
- **Pointing stability (\$)**
 - Build tools and run tests at existing facilities; define route for active stabilization;
- **Temporal and Spatial Shaping (\$)**
 - Develop efficient pulse train, temporal contrast, AO control and measurements.

- Delivering a solid baseline concept at 20 Hz with evolutionary Ti:Sa;
 - Major recent progress of *diode pumping* technology matches 20 Hz operation requirements, with frequency doubled DPSSL based pumping units;
 - Backup option with *flashlamp pumping* still available (*pros*: affordable investments and cheaper running costs – *cons*: dead end in terms of rep-rate and less attractive for technology developments.
- Design phase ongoing: preliminary 20 Hz design going technical;
- Evolution towards 100 Hz repetition rate tackling open issues:
 - Pump laser technology including diode developments
 - Amplifier design and thermal management
 - Transport and compression thermal model and criticalities;
- Significant development activities and funding needed to solve standing technical issues for forthcoming TDR phase => **EuP-LASTECH**

Discussion and questions?

